

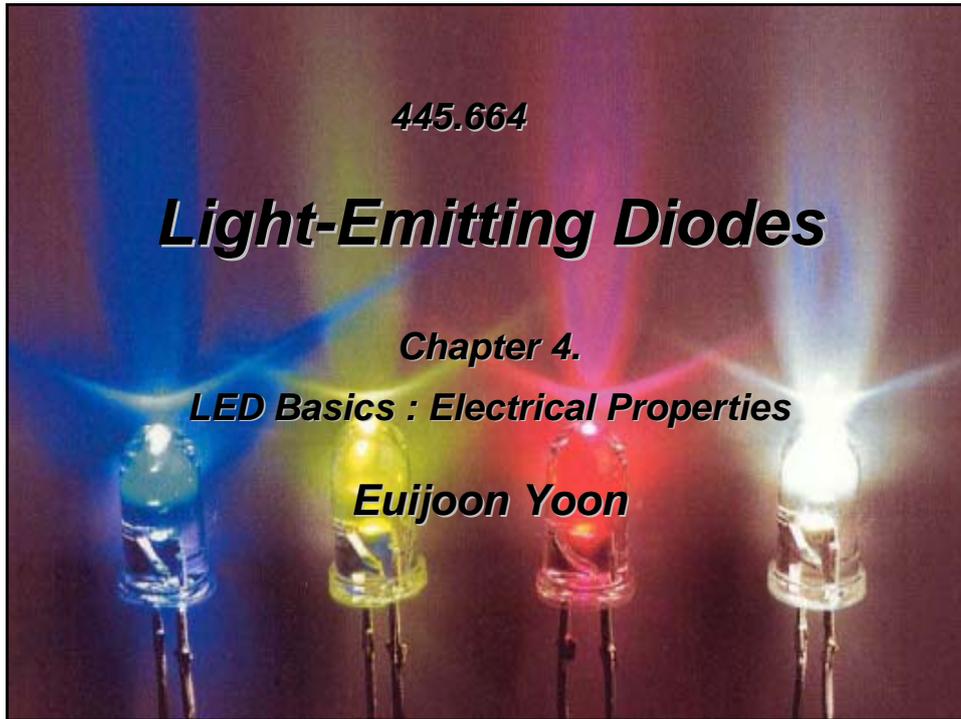
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# Light-Emitting Diodes

Chapter 4.

LED Basics : Electrical Properties

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## p-n junction band diagram

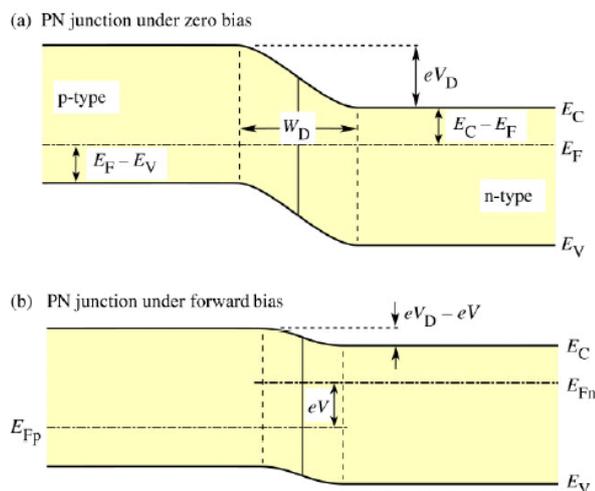


Fig. 4.1. P-N junction under (a) zero bias and (b) forward bias. Under forward bias conditions minority carriers diffuse into the neutral regions where they recombine.

## Schockley Equation

•  $V_D$  (diffusion voltage) 
$$V_D = \frac{kT}{e} \ln \frac{N_A N_D}{n_i^2}$$

$N_A, N_D$  : acceptor and donor concentration  
 $n_i$  : intrinsic carrier concentration

**The diffusion voltage represents the barrier that free carriers must overcome in order to reach the neutral region of opposite conductivity type.**

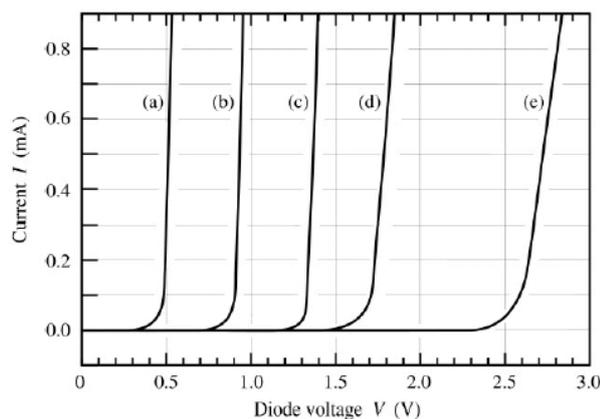
- Schockley equation (the I-V characteristic of a p-n junction)

$$I = eA \left( \sqrt{\frac{D_p}{\tau_p}} N_A + \sqrt{\frac{D_n}{\tau_n}} N_D \right) \{ e^{e(V-V_D)/kT} - 1 \}$$

$D_{n,p}$  : electron and hole diffusion constants  
 $\tau_{n,p}$  : electron and hole minority carrier lifetimes  
 $A$  : cross-sectional area,  $V$  : diode bias voltage

• **Threshold voltage ( $V_{th}$ )**  
 -the voltage at which the current strongly increase  
 -  $V_{th} \sim V_D$

## Diode current-voltage characteristics



$T = 300 \text{ K}$

(a) Ge	$E_g \approx 0.7 \text{ eV}$
(b) Si	$E_g \approx 1.1 \text{ eV}$
(c) GaAs	$E_g \approx 1.4 \text{ eV}$
(d) GaAsP	$E_g \approx 2.0 \text{ eV}$
(e) GaInN	$E_g \approx 2.9 \text{ eV}$

Fig. 4.2. Room temperature current - voltage characteristics of p-n junctions made of different semiconductors.

- Forward voltage is approximately equal to  $E_g/e$ .

## Diode forward voltage

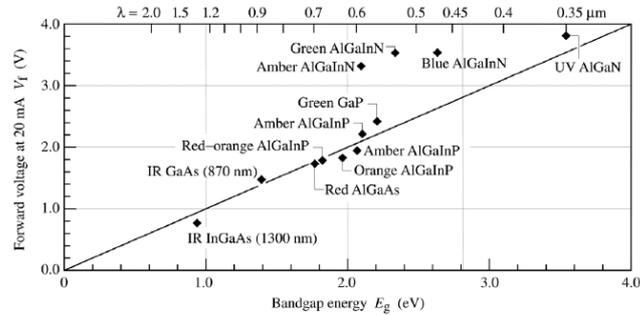


Fig. 4.3. Typical diode forward voltage versus bandgap energy for LEDs made from different materials (after Krames *et al.*, 2000; updated with UV LED data of Emerson *et al.*, 2002).

- Most semiconductor LEDs follow the solid line, except for LEDs based on III-V nitrides.

1. Large bandgap discontinuities -> additional voltage drop
2. Poor contact technology in the nitrides
3. Low p-type conductivity in bulk GaN
4. Parasitic voltage drop in the n-type buffer layer

## Deviations from the ideal I-V characteristic

- $I = I_s e^{eV/(n_{ideal} kT)}$

- $I - \frac{(V - IR_s)}{R_p} = I_s e^{e(V - IR_s)/(n_{ideal} kT)}$

$n_{ideal}$  : ideality factor

$R_s$  : parasitic series resistance

$R_p$  : parasitic parallel resistance

## Non-ideal I-V characteristics

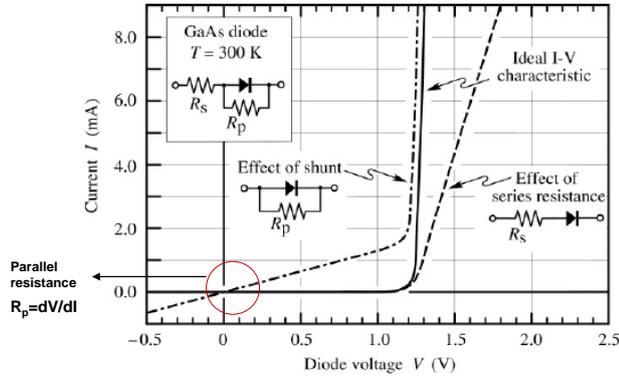


Fig. 4.4. Effect of series resistance and parallel resistance (shunt) on the I-V characteristic of a p-n-junction diode.

- **Problems area of diodes can be identified from I-V characteristic.**
  - A series resistance can be caused by contact resistance or by the resistance of the neutral region.
  - A parallel resistance can be caused by any channel that bypasses the p-n junction. The bypass can be caused by damaged regions of the p-n junction or by surface imperfections.

## Methods to determine series resistance

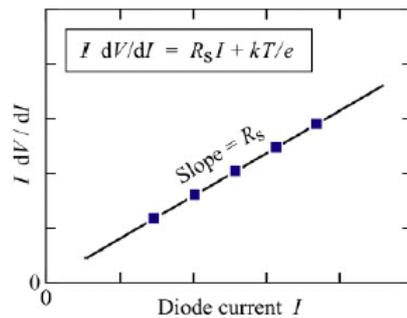


Fig. 4.5. Method for evaluating the diode series resistance. The equation shown as an inset is valid for forward bias ( $V \gg kT/e$ )

- **Method shown above suitable for series resistance measurement.**
- **At high currents, diode I-V becomes linear due to dominance of series resistance. Diode series resistance can be extracted in linear regime.**

## Carrier distribution in p-n homo- and heterojunctions

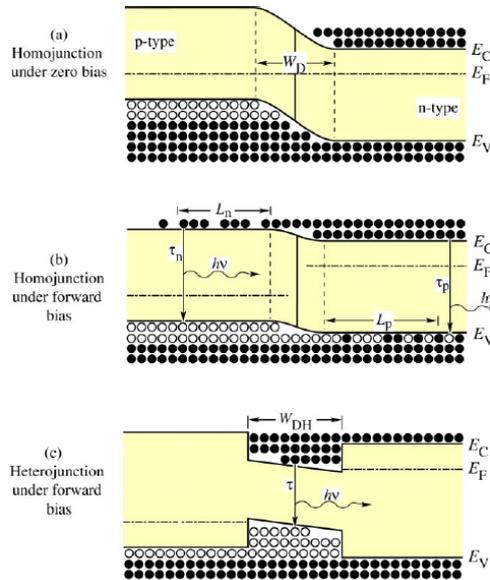


Fig. 4.6. P-N homojunction under (a) zero and (b) forward bias. P-N heterojunction (c) under forward bias. In homojunctions, carriers diffuse, on average, over the diffusion lengths  $L_n$  and  $L_p$  before recombining. In heterojunctions, carriers are confined by the heterojunction barriers.

## Double heterostructure (DH)

- Einstein relation
  - $D_n = kT\mu_n / e$
  - $D_p = kT\mu_p / e$
- Diffusion length (L)
  - $L_n = (D_n\tau_n)^{1/2}$
  - $L_p = (D_p\tau_p)^{1/2}$

- In typical semiconductors, **the diffusion length is of the order of a several micrometers.**  
ex) in p-type GaAs,  $L_n = (220 \text{ cm}^2/\text{s} \times 10^{-8} \text{ s})^{1/2} = 15\mu\text{m}$
- Minority carriers are distributed over quite a large distance. The *large recombination region in homojunctions* is not beneficial for efficient recombination.
- **Introduction of double heterostructure (DH)** makes it possible to confine the carriers in active region. The thickness of the region in which carriers recombine *is given by the thickness of the active region rather than the diffusion length.*

## The effect of heterojunctions on device resistance

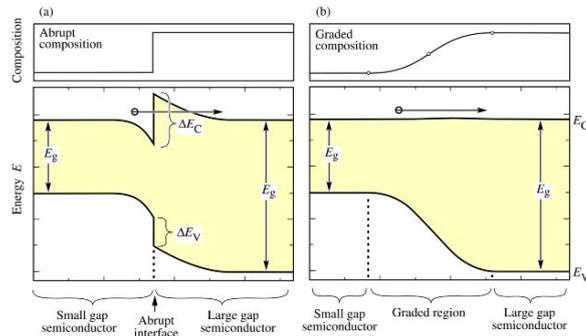


Fig. 4.7. Band diagram of (a) an abrupt n-type-n-type heterojunction and (b) a graded heterojunction of two semiconductors with different bandgap energy. The abrupt junction is more resistive than the graded junction due to the electron barrier forming at the abrupt junctions.

- One of the problem introduced by heterostructures is *the resistance caused by the heterointerface* and it can have a strong deleterious effect on device performance, especially in high-power devices.
- The resistance introduced by abrupt heterostructures can be completely eliminated by *parabolic grading*.

## Grading of heterostructures

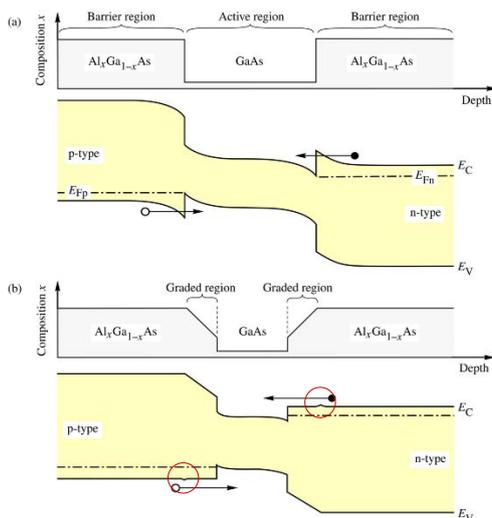


Fig. 4.8. Band diagram of (a) an abrupt double heterostructure and (b) a graded double heterostructure. The barrier-well interface of the abrupt junction is more resistive than the graded junction due to barriers forming at the interfaces.

$$\phi = \frac{eN_D}{2\epsilon} x^2$$

- In order to compensate for the parabolic shape of the depletion potential, the composition of the semiconductor is varied parabolically as well, so that an overall flat potential results.

- If the potential created in the depletion region is equal to  $\Delta E_g/e$ , then electrons will no longer transfer to the small-bandgap material. The thickness of the depletion region is,,,

$$W_D = \sqrt{\frac{2\epsilon\Delta E_C}{e^2N_D}}$$

- The “spikes” are a result of the linear grading assumed, and would not result for parabolic grading.

## Carrier loss in double heterostructures

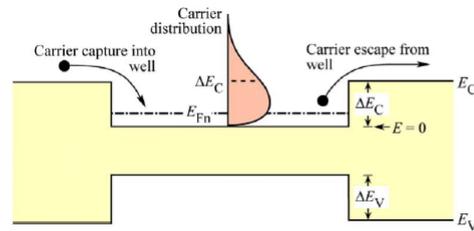


Fig. 4.9. Carrier capture and escape in a double heterostructure. Also shown is the carrier distribution in the active layer.

- The concentration of electrons with energy higher than the barrier

$$n_B = \int_{E_B}^{\infty} \rho_{\text{DOS}} f_{\text{FD}}(E) dE \quad \longrightarrow \quad n_B = N_C e^{-(E_{Fn} - E_B)/kT}$$

(Fermi-Dirac distribution)  (Boltzmann distribution)

- The diffusion current density of electrons leaking over the barrier

$$J_n|_{x=0} = -eD_n \left. \frac{dn_B(x)}{dx} \right|_{x=0} = -eD_n \frac{n_B(0)}{L_n}$$

$$n_B(x) = n_B(0) e^{-x/L_n} = N_C e^{-(E_B - E_{Fn})/kT} e^{-x/L_n}$$

## Carrier overflow in double heterostructures

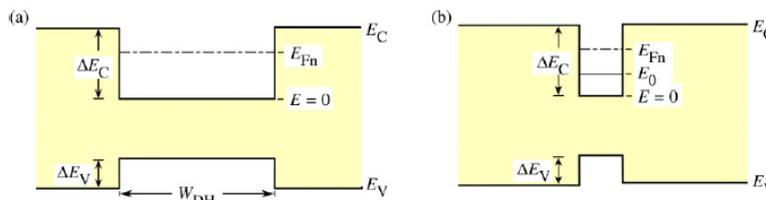


Fig. 4.10. Fermi level ( $E_{Fn}$ ) and subband level ( $E_0$ ) in (a) double hetero-structure and (b) a quantum well structure.

- The current density at which the active region overflows,,,

$$J_{\text{overflow}} = \left( \frac{4N_C}{3\sqrt{\pi}} \right)^2 \left( \frac{\Delta E_C}{kT} \right)^3 eB W_{\text{DH}} \quad \text{(for DH structure LED)}$$

$$J_{\text{overflow}} = \left[ \frac{m^*}{\pi(\hbar/2\pi)^2} (\Delta E_C - E_0) \right]^2 \frac{eB}{W_{\text{QW}}} \quad \text{(for QW structure LED)}$$

## Carrier overflow - For DH structure LED

- The rate equation of carrier supply to (by injection) and removal from the active region (by recombination) is given by

$$\frac{dn}{dt} = \frac{J}{eW_{DH}} - Bnp \quad (B: \text{the bimolecular recombination coefficient})$$

- For high injection densities:  $n=p$
- Under steady-state conditions ( $dn/dt=0$ ),  $\rightarrow n = \sqrt{\frac{J}{eBW_{DH}}}$

- In the high-density approximation, the Fermi level is given by

$$\frac{E_F - E_C}{kT} = \left( \frac{3\sqrt{\pi} n}{4 N_C} \right)^{2/3} \quad (N_C: \text{effective density of states})$$

- At high injection levels, the Fermi energy rises and will eventually reach the top of the barrier. At that point,  $E_F - E_C = \Delta E_C$ . Using this value, the current density at which the active region overflows is given by

$$J_{\text{overflow}} = \left( \frac{4N_C}{3\sqrt{\pi}} \right)^2 \left( \frac{\Delta E_C}{kT} \right)^3 eBW_{DH}$$

## Carrier overflow - For QW structure LED

- For QW structures, we must employ the 2D density of states, rather than the 3D density of states. The Fermi level in a QW with one quantized state with energy  $E_0$  is given by

$$\frac{E_F - E_0}{kT} = \ln \left[ \exp \left( \frac{n^{2D}}{N_C^{2D}} \right) - 1 \right] \quad \begin{array}{l} (n^{2D}: \text{the 2D carrier density per cm}^2, \\ N_C^{2D}: \text{the effective 2D density of states}) \end{array}$$

- $N_C^{2D}$  is given by

$$N_C^{2D} = \frac{m^*}{\pi(\hbar/2\pi)^2} kT$$

- The high-degeneracy approximation (at high carrier densities) is employed and one obtains

$$E_F - E_0 = \frac{\pi(\hbar/2\pi)^2}{m^*} n^{2D}$$

## Carrier overflow - For QW structure LED

- The rate equation for the QW of carrier supply to (by injection) and removal from the active region (by recombination) is given by

$$\frac{dn^{2D}}{dt} = \frac{J}{e} - B^{2D} n^{2D} p^{2D}$$

( $B^{2D} \approx B/W_{QW}$  : the bimolecular recombination coefficient for a 2D structure)

- For high injection densities:  $n^{2D} = p^{2D}$
- Under steady-state conditions ( $dn^{2D}/dt=0$ ),  $\rightarrow n^{2D} = \sqrt{\frac{J}{eB^{2D}}} = \sqrt{\frac{JW_{QW}}{eB}}$
- At high injection levels, the Fermi energy will reach the top of the barrier. At that point,  $E_F - E_0 = \Delta E_C - E_0$ . Using this value, the current density at which the active region overflows is given by

$$J_{\text{overflow}} = \left[ \frac{m^*}{\pi(\hbar/2\pi)^2} (\Delta E_C - E_0) \right]^2 \frac{eB}{W_{QW}}$$

## Saturation of output power due to leakage

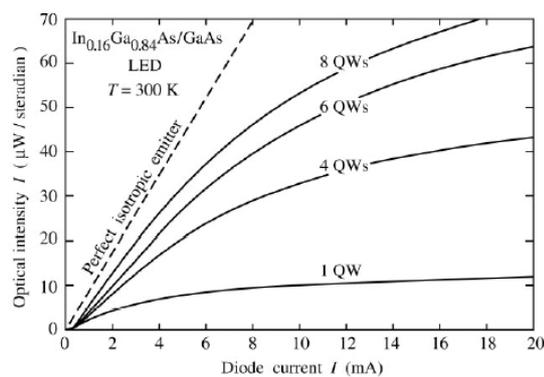


Fig. 4.11. Optical intensity emitted by  $\text{In}_{0.16}\text{Ga}_{0.84}\text{As} / \text{GaAs}$  LEDs with active regions consisting of 1, 4, 6, and 8 quantum wells and theoretical intensity of a perfect isotropic emitter (dashed line) (after Hunt *et al.*, 1992).

- In order to avoid the carrier overflow, high current LEDs must employ *thick* DH active regions, or *many* QWs of multiple QW (MQW) active regions, or a large injection (contact) area.

## Electron blocking layers

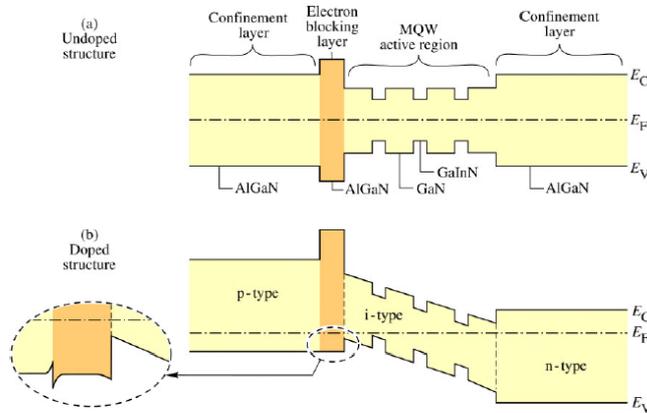


Fig. 4.12. Illustration of an AlGaIn current blocking layer in an AlGaIn / GaN / GaInN multi-quantum well (MQW) LED structure. (a) Band diagram without doping. (b) Band diagram with doping. The Al content in the electron blocking layer is higher than in the p-type confinement layer.

- The barrier in the valence band is screened by free carriers so that there is *no barrier* to the flow of *holes* in the p-type confinement layer.

## Diode forward voltage

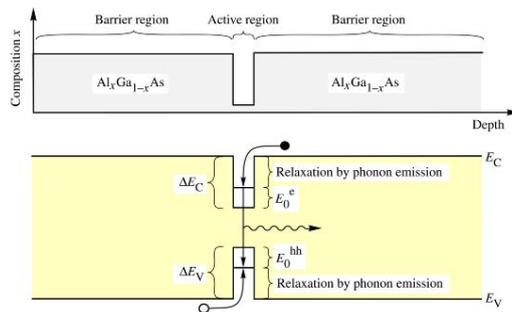


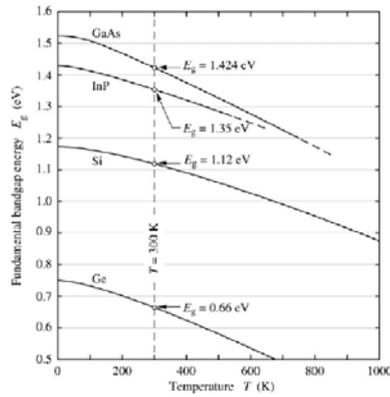
Fig. 4.13. (a) Chemical composition and (b) band diagram of a quantum well structure illustrating the energy loss of carriers as they are captured into the quantum well.

- The total voltage drop across a forward-biased LED is given by

$$V = \frac{E_g}{e} + IR_s + \frac{\Delta E_C - E_0}{e} + \frac{\Delta E_V - E_0}{e}$$

- One finds experimentally that the diode voltage can be *slightly lower* than the *minimum value* predicted by above Eq'n, i.e.  $\sim E_g/e$

## Temperature dependence of diode voltage



$$E_g = E_g(0\text{K}) - \frac{\alpha T^2}{T + \beta}$$

	$E_g(0\text{K})$	$\alpha$ ( $10^{-4} \frac{\text{eV}}{\text{K}}$ )	$\beta$ (K)
GaAs	1.519	5.41	204
InP	1.425	4.50	327
Si	1.170	4.73	636
Ge	0.744	4.77	235

Fig. 4.14. Fundamental bandgap energy of GaAs, InP, Si, and Ge as a function of temperature. The bandgap energy is approximated by a parabolic equation with the fitting parameters  $\alpha$  and  $\beta$ .

- The temperature dependence of the diode voltage

$$V(T) = \frac{kT}{e} \ln \frac{I}{I_s^*} + \frac{E_g(T)}{e}$$

- first term : due to the changes of the Fermi level with temperature
- The contribution of the first term is generally smaller than the contribution of the second term.

- Diode voltage decreases with increasing temperature due to decrease in energy gap and increase in saturation current density.

## Temperature dependence of diode voltage

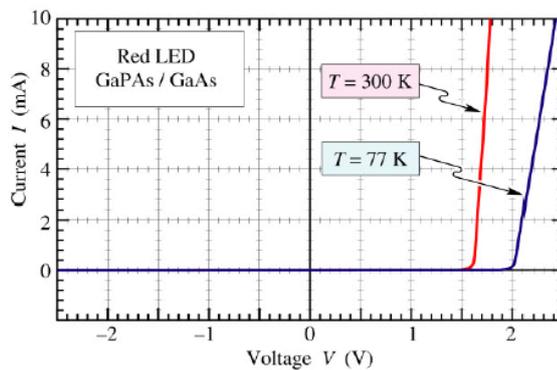


Fig. 4.15. Current-voltage characteristic of a GaAsP / GaAs LED emitting in the red part of the visible spectrum, measured at 77 K and 300 K. The threshold voltages are 2.0 V and 1.6 V, at 77 K and 300 K respectively.

- Diode forward voltage can be used to assess junction temperature with high accuracy.

## Drive circuits

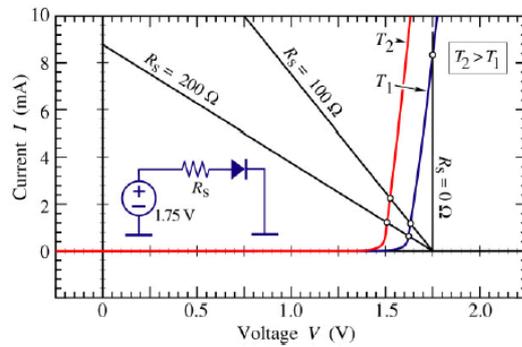


Fig. 4.16. LED drive circuit with series resistance  $R_s$ . The intersection between the diode  $I$ - $V$ s and the load lines are the points of operation. Small series resistances result in an increased diode current at high temperatures, thus allowing for compensation of a lower LED radiative efficiency.

- Constant current-drive circuit
- Constant voltage-drive circuit
- What are the advantages and disadvantages?